

<b>Notice of References Cited</b>	Application/Control No. 10/519,126		Applicant(s)/Patent Under Reexamination ITO ET AL.	
	Examiner Joseph M. Pelham		Art Unit 3742	Page 1 of 1

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*	B	US-5,105,556	04-1992	Kurokawa et al.	34/470
*	C	US-5,776,296	07-1998	Matthews, Robert Roger	134/902
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*	G	US-4,186,032	01-1980	Ham, William E.	134/902
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**NON-PATENT DOCUMENTS**

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	V	Partial machine translation of JP2001-252550, Apparatus for Supplying Steam, 18.09.2001, Masahiro et al
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.